Notice of Allowability	Application No.	Applicant(s)	
	10/750,890	KIM ET AL.	ω
	Examiner	Art Unit	
	Mai-Huong Tran	2818	
The MAILING DATE of this communication apperaisable of the communication apperaisable of the communication apperaisable of the communication apperaisable of the communication appears of the communication appears of the communication appears of the communication ap	(OR REMAINS) CLOSED in this app or other appropriate communication GHTS. This application is subject to	olication. If not include will be mailed in due o	ed course. THIS
1. 🖾 This communication is responsive to <u>1/5/2004</u> .			
2. ☑ The allowed claim(s) is/are <u>1-12</u> .			
3. $igotimes$ The drawings filed on <u>05 January 2004</u> are accepted by the	e Examiner.		
4. Acknowledgment is made of a claim for foreign priority una) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 5. A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give (a) including changes required by the Notice of Draftspers 1) hereto or 2) to Paper No./Mail Date (b) including changes required by the attached Examiner's Paper No./Mail Date Identifying Indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in til. 7. DEPOSIT OF and/or INFORMATION about the depose attached Examiner's comment regarding REQUIREMENT.	been received. been received in Application Nocuments have been received in this application. In the submitted in the s	complying with the requestion of the front (not the fl).	uirements OTICE OF
	5. Notice of Informal P. 6. Interview Summary Paper No./Mail Dat 7. Examiner's Amendn 8. Examiner's Stateme 9. Other David Nelms Dervisory Patent Examiner Describing Center 2800	(PTO-413), e nent/Comment	

DETAILED ACTION

Reason for allowance

The following is an examiner's statement of reason for allowance: None of the references of record teaches or suggests the claimed Thin Film Transistor Panel for Liquid Crystal Display having first and second pixel electrodes formed in a pixel area defined by the intersections of the first and the second signal wires and including a plurality of subareas partitioned by cutouts; a direction control electrode formed in the pixel area and including a portion overlapping at least one of the cutouts; and a first thin film transistor connected to the direction control electrode, the first signal wire, and the second signal wire.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance".

Conclusion

Any inquiry concerning this communication on earlier communications from the examiner should be directed to Mai-Huong Tran, (571) 272-1796. The examiner can

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normally be reached on Monday-Thursday from 8:00 AM to 6:30 PM. The examiner's supervisor, David Nelms can be reached on (571) 272-1787.

The fax phone number for the organization where this application or proceeding is assigned is (703) 872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR, Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Mai-Huong Tran

David Nelms
Supervisory Patent Examiner
Technology Center 2800